

Synthetic Quartz Crystal - Specifications and guidelines  
for use

## EESTI STANDARDI EESSÕNA

## NATIONAL FOREWORD

See Eesti standard EVS-EN 60758:2016 sisaldab Euroopa standardi EN 60758:2016 ingliskeelset teksti.	This Estonian standard EVS-EN 60758:2016 consists of the English text of the European standard EN 60758:2016.
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## English Version

**Synthetic quartz crystal - Specifications and guidelines for use  
(IEC 60758:2016)**

Cristal de quartz synthétique - Spécifications et lignes  
directrices d'utilisation  
(IEC 60758:2016)

Synthetischer Quarzkristall - Festlegungen und Leitfaden  
für die Anwendung  
(IEC 60758:2016)

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## European foreword

The text of document 49/1185/FDIS, future edition 5 of IEC 60758, prepared by IEC/TC 49 "Piezoelectric, dielectric and electrostatic devices and associated materials for frequency control, selection and detection" was submitted to the IEC-CENELEC parallel vote and approved by CENELEC as EN 60758:2016.

The following dates are fixed:

- latest date by which the document has to be (dop) 2017-04-07  
implemented at national level by  
publication of an identical national  
standard or by endorsement
- latest date by which the national (dow) 2019-10-07  
standards conflicting with the  
document have to be withdrawn

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## Annex ZA (normative)

### Normative references to international publications with their corresponding European publications

The following documents, in whole or in part, are normatively referenced in this document and are indispensable for its application. For dated references, only the edition cited applies. For undated references, the latest edition of the referenced document (including any amendments) applies.

NOTE 1 When an International Publication has been modified by common modifications, indicated by (mod), the relevant EN/HD applies.

NOTE 2 Up-to-date information on the latest versions of the European Standards listed in this annex is available here: [www.cenelec.eu](http://www.cenelec.eu)

<u>Publication</u>	<u>Year</u>	<u>Title</u>	<u>EN/HD</u>	<u>Year</u>
IEC 60068-1	2013	Environmental testing - Part 1: General and guidance	EN 60068-1	2014
IEC 60122-1	2002	Quartz crystal units of assessed quality - Part 1: Generic specification	EN 60122-1	2002
IEC 60410	-	Sampling plans and procedures for inspection by attributes	-	-
IEC 61994	Series	Piezoelectric and dielectric devices for frequency control and selection - Glossary	-	-

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## INTRODUCTION

The reason for adding synthetic quartz crystal for optical application to this International Standard is as follows.

Quartz crystal produced for optical applications is produced by many of the same suppliers manufacturing quartz for electronic applications. The equipment and methods to produce optical quartz are similar to those used in the production of electronic quartz. Also, with a few exceptions the characterization methods of electronic and optical material are similar. Therefore, IEC 60758 serves as the proper basis for including addenda related to quartz crystal for optical applications.